

1c971 U.S. PTO  
10/083440

02/26/02

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10083440	FILING DATE 02/26/2002	CLASS 438	SUBCLASS 14	GAU 2812	EXAMINER Q. HOANG
<b>**APPLICANTS:</b> Ushiki Takeo; Yamada Keizo; Itagaki Yohsuke; Tsujide Tohru; 2812					
<b>**CONTINUING DATA VERIFIED:</b>					
<b>** FOREIGN APPLICATIONS VERIFIED:</b> JAPAN 2001-58075 03/02/2001					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO NEKW 19.480	
<b>TITLE :</b> Surface contamination analyzer for semiconductor wafers, method used therein and process for fabricating semiconductor device					
U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)					

BEST AVAILABLE COPY

<b>NOTICE OF ALLOWANCE MAILED</b>		<b>CLAIMS ALLOWED</b>	
		Total Claims	Print Claim for O.G.
<b>ISSUE FEE</b>		<b>DRAWING</b>	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> <b>TERMINAL</b> <b>DISCLAIMER</b>		<b>PREPARED FOR ISSUE</b> <b>Application Examiner</b>	
<b>WARNING:</b> The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35.			